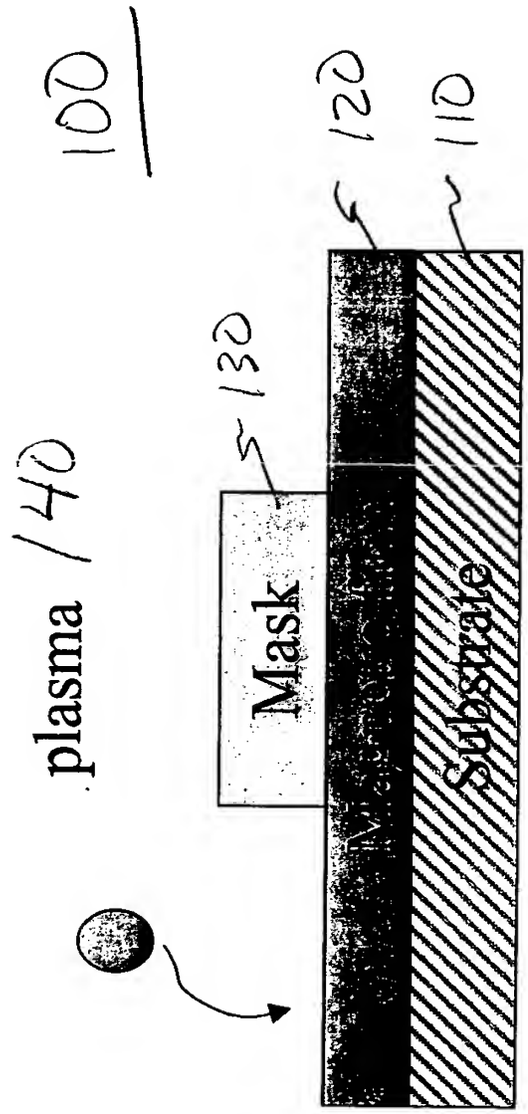


Fig. 1

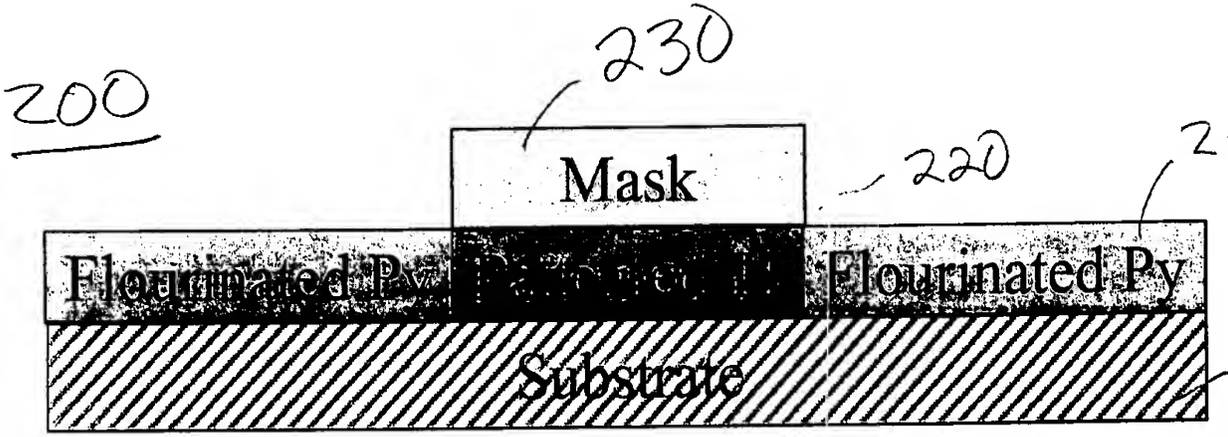


Fig. 2A
(Flourination)

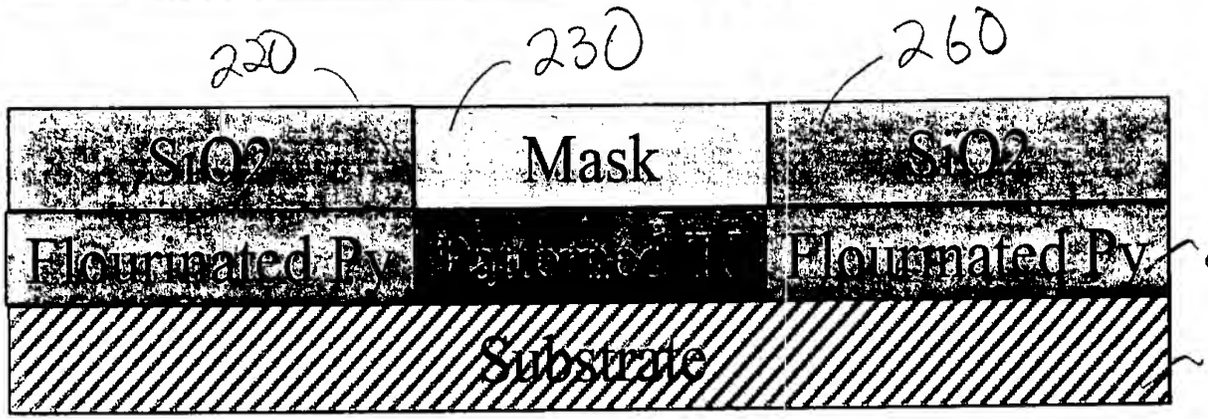


Fig. 2B
(Passivation)

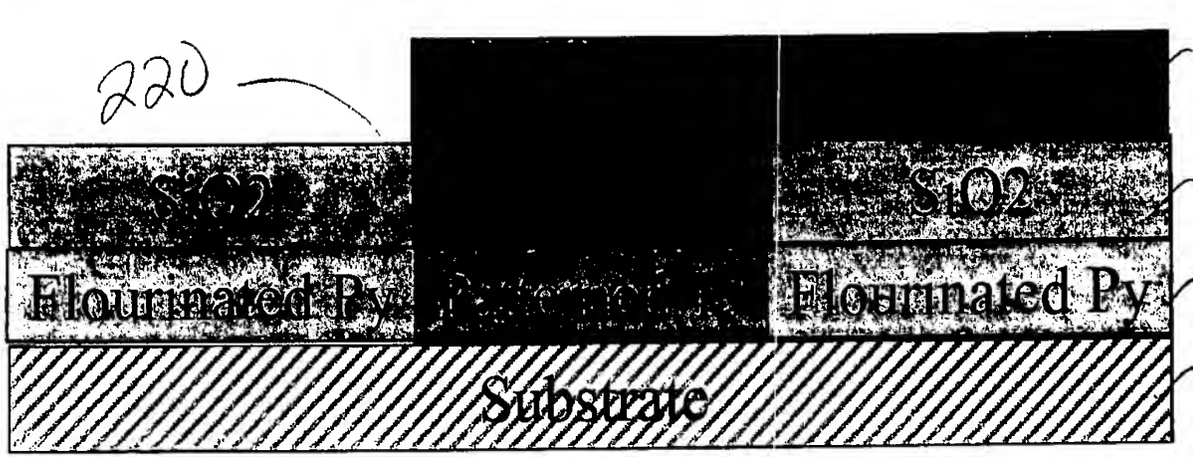
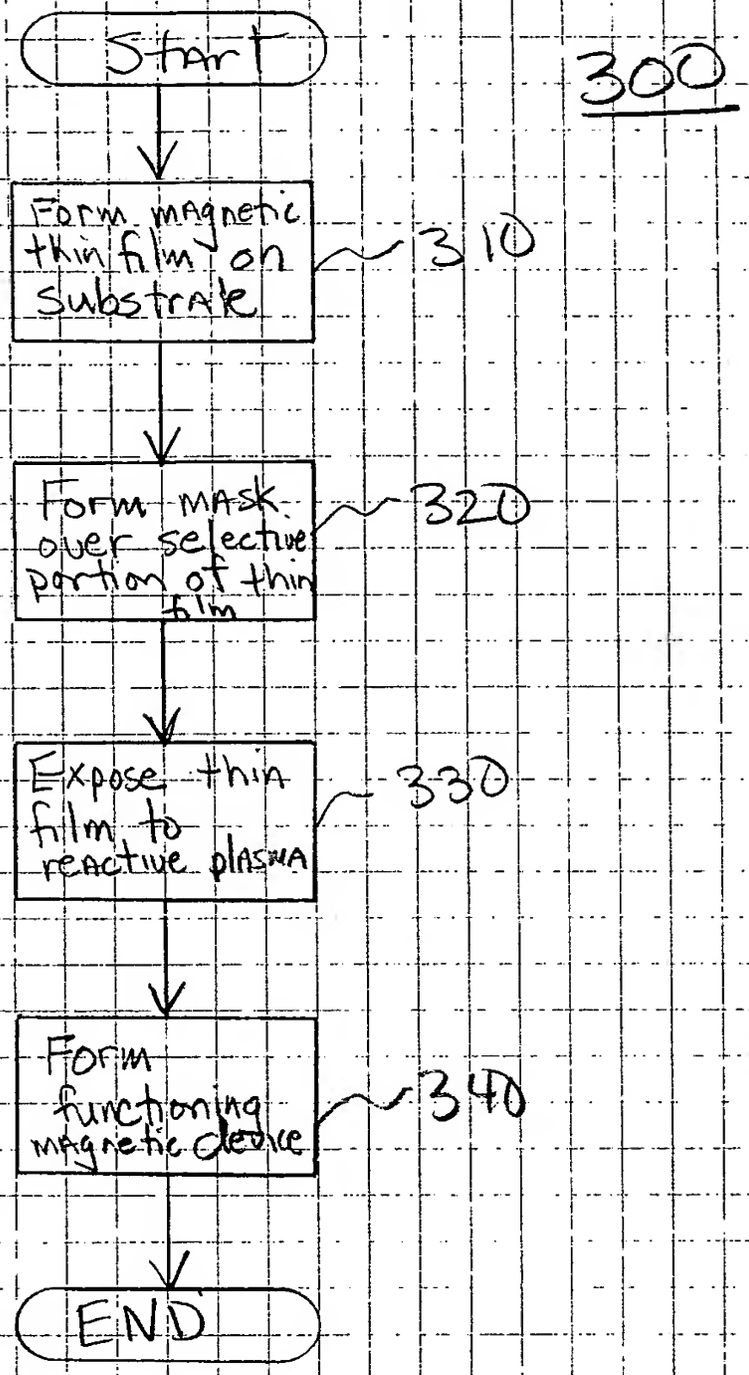


Fig. 2C
(Contact)

Figure 3


Start
300
Form magnetic thin film on substrate
310
Form MASK over selective portion of thin film
320
Expose thin film to reactive plasma
330
Form functioning magnetic device
340
END

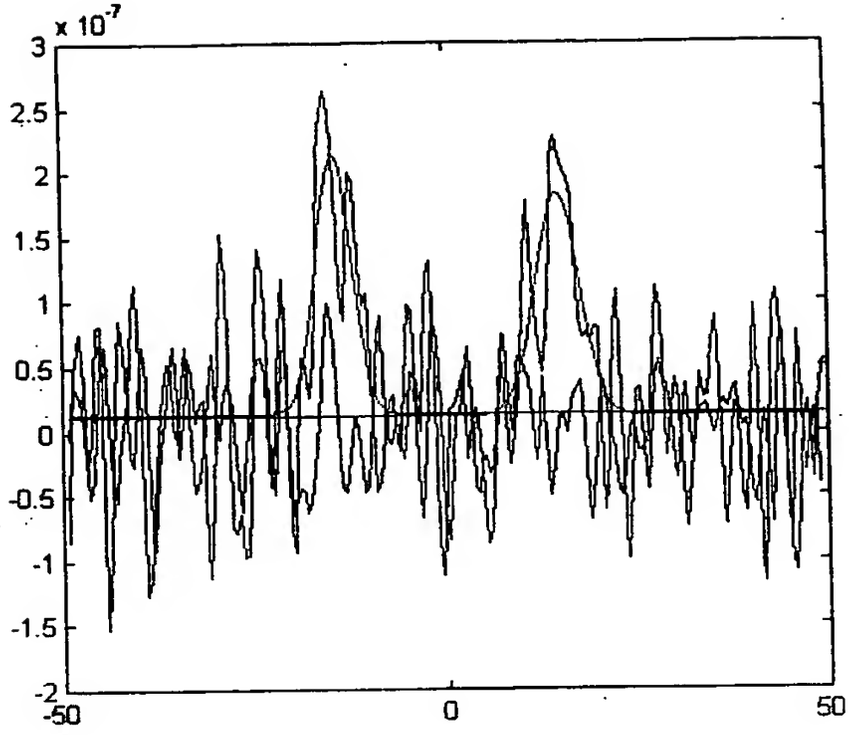


Figure 4A

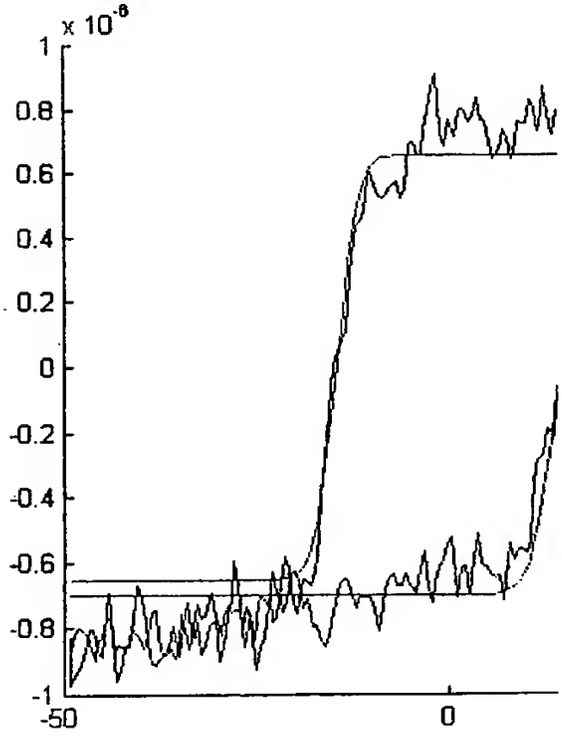


Figure 4B